Programme: M-ERA.NET Call 2021

Call topic: Innovative surfaces, coatings and interfaces

Full title: Ion Implantation for Innovative Interface modifications in BAttery

and **G**raphene-enabled **S**ystems

Acronym: I4BAGS



Belgian participants: Materia Nova R&D Center and IONICS S.A.

Polish participants: QWED SP. Z O. O. and Institute of Microelectronics and Photonics

Funding organisations: Service Public de Wallonie (Belgium) and National Centre for Research and Development (Poland)

Duration: 01.09.2022 - 31.08.2025















Institute of Microelectronics and Photonics

General objectives:

- Incorporate ion implantation to boost the performance of solid-state batteries
- Incorporate ion implantation to boost the performance of graphene-on-SiC devices
- Develop advanced microwave and mm-Wave characterisation methodologies
- Develop demonstrators and high-score publications





Tymoteusz Ciuk

Łukasiewicz Research Network



Institute of Microelectronics and Photonics, Warsaw, Poland



Graphene on Silicon Carbide Platform

for Magnetic Field Detection

under Extreme Temperature Conditions

and Neutron Radiation



Graphene on Silicon Carbide Platform

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Thermal stability of transport properties

Two-dimensional character Why graphene on SiC? Hole mobility up to 5000 cm²/Vs

Fixed hole concentration



Epitaxy: Chemical Vapor Deposition (CVD)

Carbon source: methane or propane

Substrate: 4H-SiC(0001) or 6H-SiC(0001)

Type: semi-insulating on-axis

Dimensions: 20 mm x 20 mm



dx.doi.org/10.1016/j.carbon.2015.06.032 dx.doi.org/10.1016/j.carbon.2016.01.093

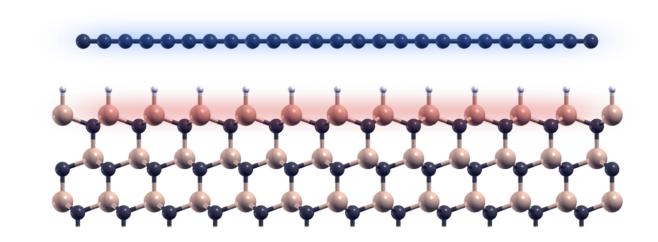


Hydrogen intercalation: quasi-free-standing graphene

Spontaneous polarization vector: P₀

Surface-bound pseudo charge: P₀/e

Reflected in QFS graphene as: $-P_0/e$



doi.org/10.1016/j.apsusc.2020.148668

doi.org/10.1016/j.apsusc.2023.158617

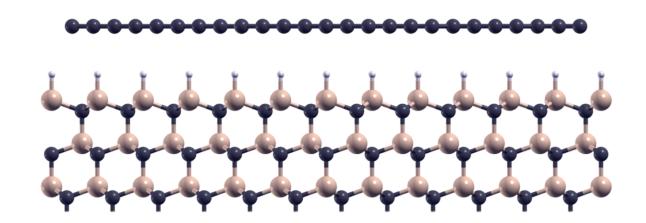


Hydrogen intercalation: quasi-free-standing graphene

Polarization effect: positive

On 4H-SiC(0001): $p = +1.2 E13 cm^{-2}$

On 6H-SiC(0001): $p = +7.5 E12 cm^{-2}$



doi.org/10.1016/j.apsusc.2020.148668

doi.org/10.1016/j.apsusc.2023.158617

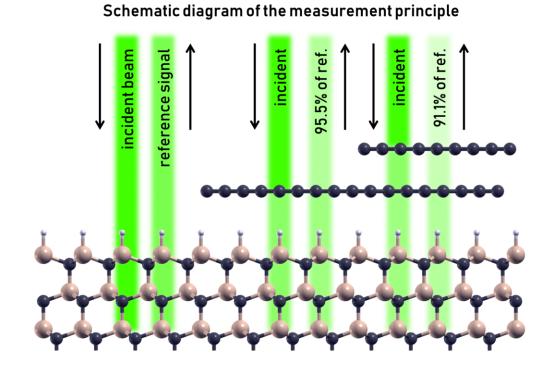


Basis: signal intensity attenuation

Implementation: shadow cast on LO 964 cm⁻¹

Number of layers N: fractional and statistical

Alternative to: 2D width, 2D-to-G ratio



doi.org/10.1016/j.physe.2021.114853

doi.org/10.1016/j.apsusc.2022.155054



Graphene on Silicon Carbide Platform

for Magnetic Field Detection

under Extreme Temperature Conditions

and Neutron Radiation

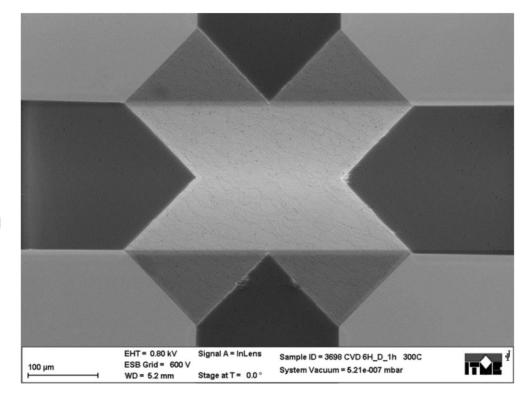


Principle of operation: classical Hall effect

Configuration: van der Pauw

Active area: equal-arm cross 100 μm x 300 μm

Total dimensions: 1.4 mm x 1.4 mm

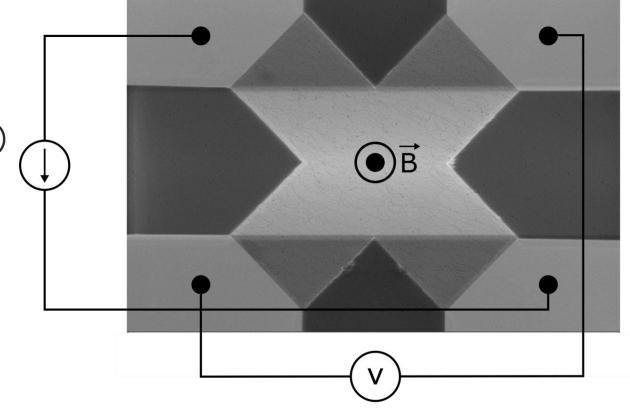


doi.org/10.1016/j.carbon.2018.07.049



Input: direct current

Output: offset voltage + Hall voltage(\overrightarrow{B})





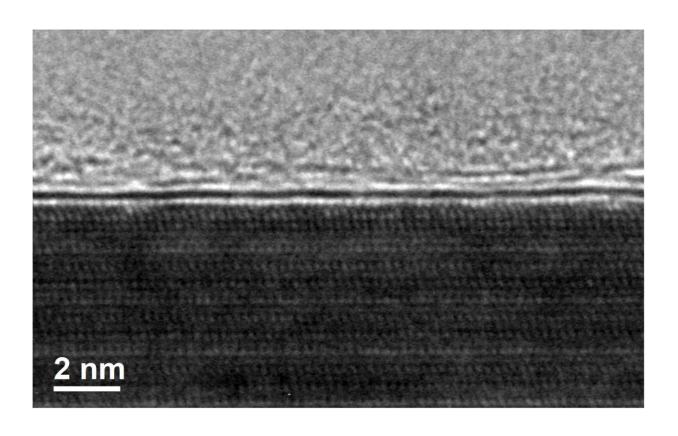
Graphene on Silicon Carbide Platform for Magnetic Field Detection under Extreme Temperature Conditions and Neutron Radiation

Passivation: aluminum oxide

Process: atomic layer deposition

Precursors: TMA and DI

Purpose: environmental protection



doi.org/10.1016/j.physe.2022.115264

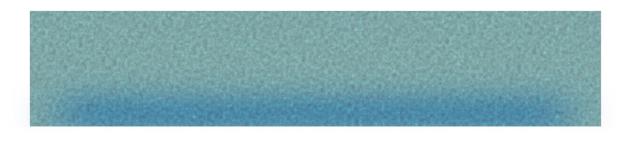


100-nm a-Al2O3: excess positive charge

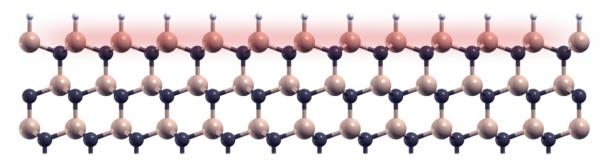
Polarization effect: negative

On 4H-SiC(0001): $p = +7.5 E12 cm^{-2}$

On 6H-SiC(0001): $p = +4.6 E12 cm^{-2}$

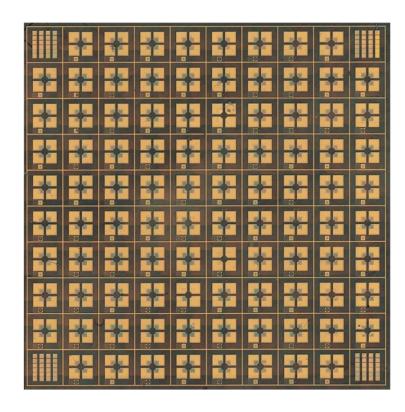


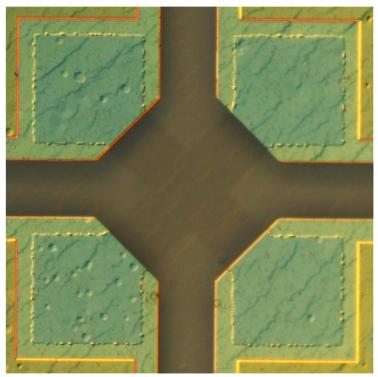


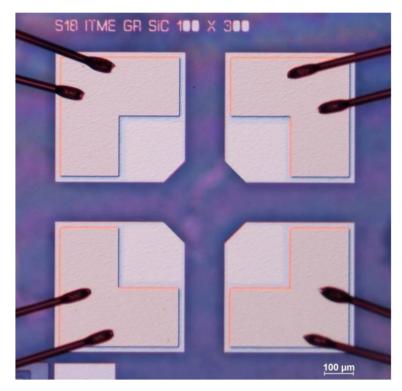


doi.org/10.1016/j.apsusc.2020.148668









doi.org/10.1016/j.physe.2021.114853 doi.org/10.1016/j.physe.2022.115264

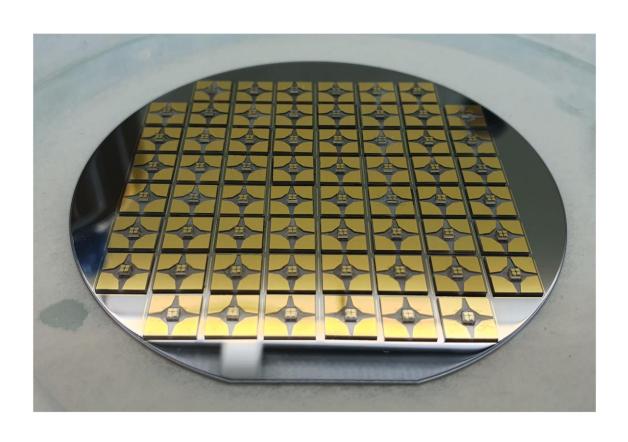


Mounting: custom holders

Feed current: < 10 mA

Magnetic induction: 0.55 T

Temperatures: up to 500 °C



10.1109/TED.2019.2915632



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Current-mode sensitivity: $\frac{dU_{Hall}}{dB}/I$

Expressed in: V/AT

Inversely proportional to: hole density

Polytype dependent: Yes



Two platforms: 6H-SiC and 4H-SiC

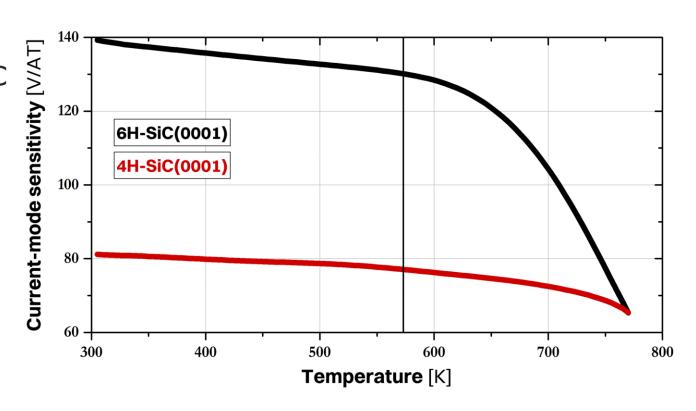
Two levels of sensitivity:

6H-SiC: 140 V/AT

4H-SiC: 80 V/AT

Start temperature: RT

End temperature: 770 K (497 °C)





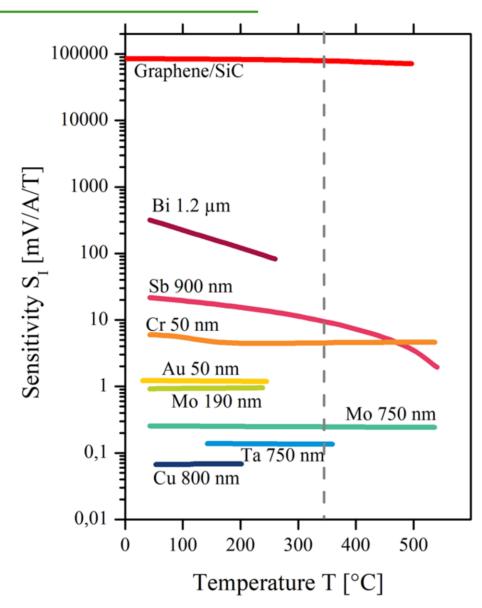
Alternative platforms: Bi, Sb, Cr, Au, Mo, Ta, Cu

Sensitivities: 0.1 mV/AT - 100 mV/AT

Start temperature: 50 °C

End temperature: 770 K (500 °C)

Source: Entler S., et al., Sensors 2021, 21, 721.

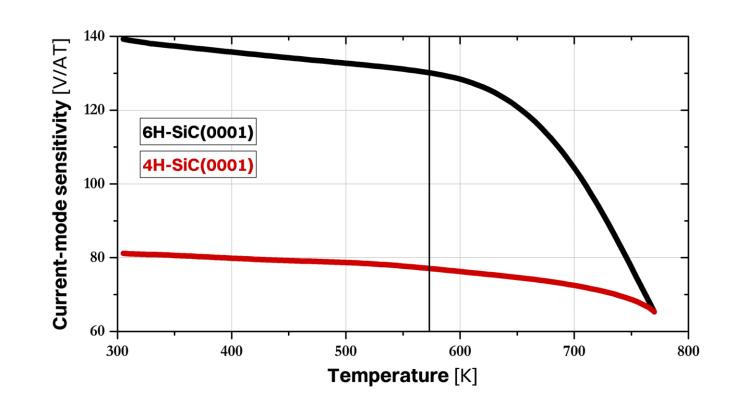


Down-bending: >300 °C

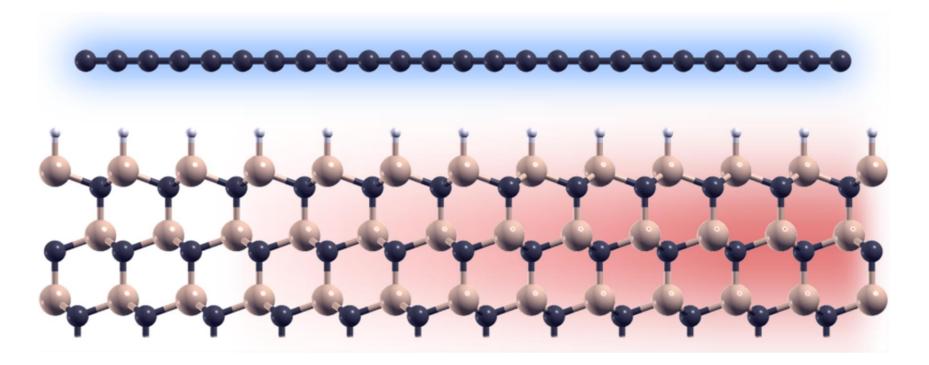
Physical degradation: No

Fully reversible: Yes

Possible hallmark: Yes

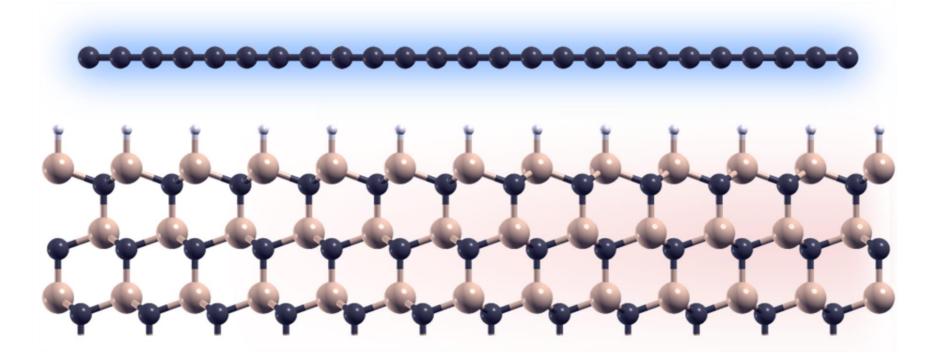


Double-carrier transport: holes in QFS graphene and thermally-activated electrons emitted in the bulk of the semi-insulating 6H-SiC(0001) and 4H-SiC(0001)





Double-carrier transport: holes in QFS graphene and thermally-activated electrons emitted in the bulk of the semi-insulating 6H-SiC(0001) and 4H-SiC(0001)





Graphene on Ion-implanted Silicon Carbide Platform

for Magnetic Field Detection

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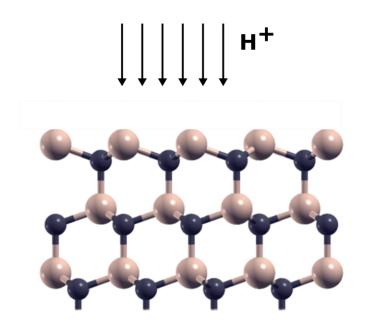
As revealed by High-Resolution Photo-Induced Transient Spectroscopy (HRPITS)

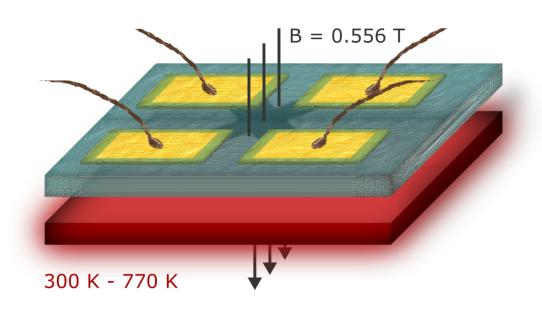
SI vanadium-compensated 6H-SiC has 9 trap levels

SI HP intrinsically-compensated 4H-SiC has 17 trap levels



Pre-epitaxially modify the semi-insulating high-purity 4H-SiC by **implanting hydrogen (H**⁺**) ions**





doi.org/10.1016/j.cartre.2023.100303

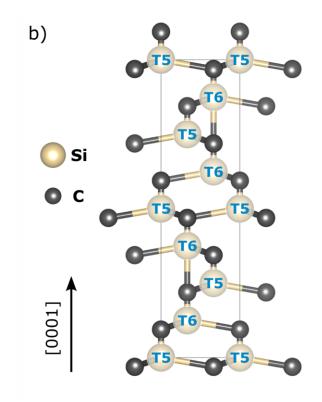
Pre-epitaxial bombardment: H⁺ ions

Energy: 20 keV

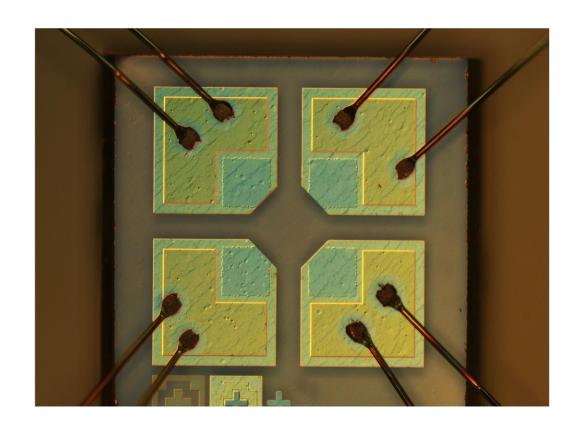
Objective: elimination of deep electron traps related to silicon vacancies in the charge state (2-/-) occupying the h and k sites of the 4H-SiC lattice

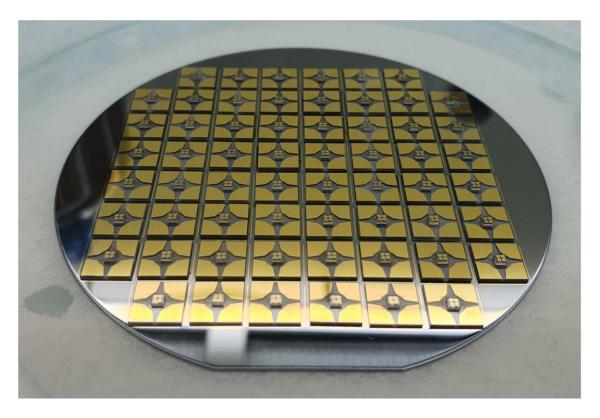
T5_{4H}: $E_a = 708 \text{ meV}$

T6_{4H}: $E_a = 753 \text{ meV}$



doi.org/10.1016/j.cartre.2023.100303





Platform: 4H-SiC

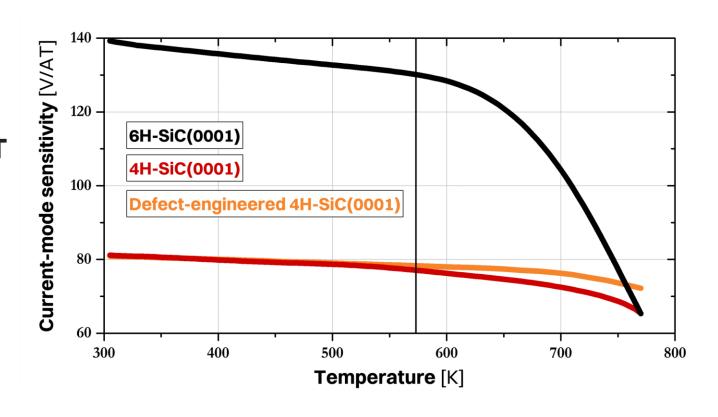
Type: Ion-implanted

Current-mode sensitivity: 80 V/AT

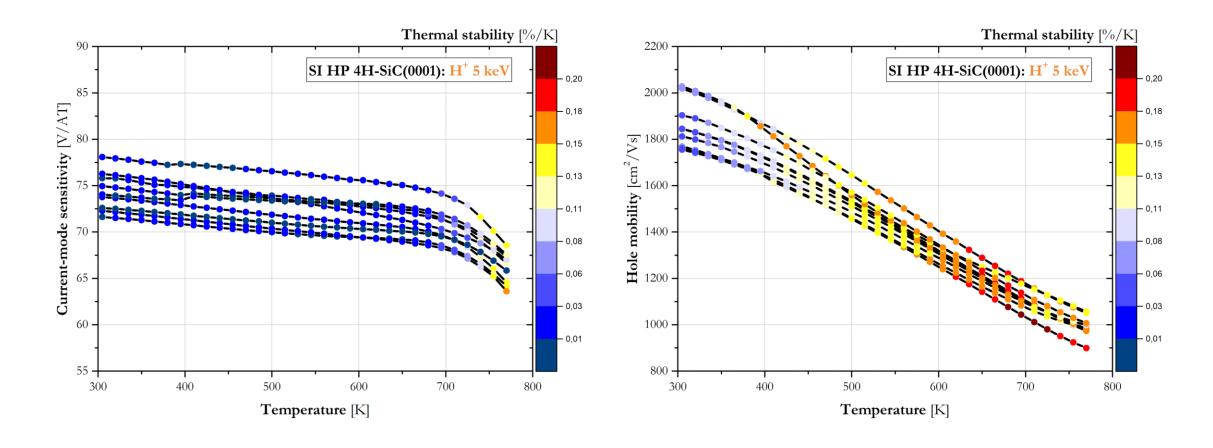
End temperature: 770 K (497 °C)

Advantages: more linear,

less dispersed









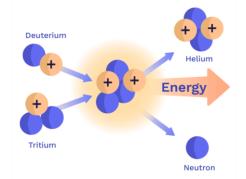
EUROfusion: transition from science-driven International Thermonuclear Experimental Reactor (ITER) to the industry-driven **DEMO**-class reactor

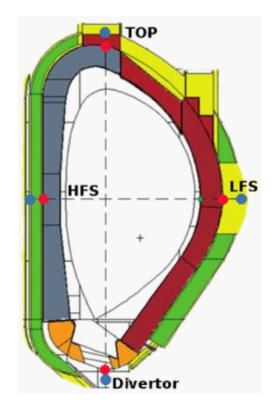
Magnetic diagnostics: 5.8 T with 2.5-mT accuracy

Ex-vessel: 473 K

In-vessel: 773 K (500 °C)

Hazard: neutron radiation up to 2E18 cm⁻²





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Completed and published:

Fast neutron fluence of **6.7 E17** cm⁻² (peak at 1 MeV) Exposure time: **5 days**

Completed but not yet published:

Fast neutron fluence of 2.0 E18 cm⁻² (peak at 1 MeV) Exposure time: 10 days

Fast neutron fluence of 4.0 E18 cm⁻² (peak at 1 MeV) Exposure time: 23 days

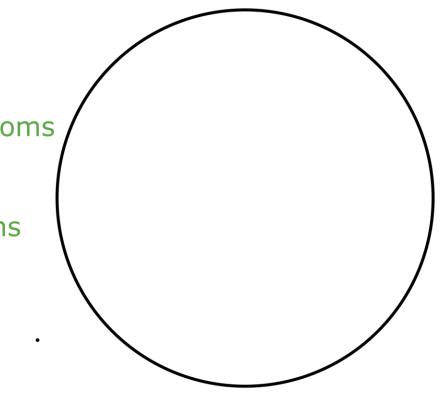


Number of carbon atoms in graphene: 3.8 E15 cm⁻²

Neutron fluence (dose): E17 - E18 cm⁻²

There are 100 to 1000 more neutrons than carbon atoms

Neutrons are 100000 times smaller than carbon atoms



doi.org/10.1016/j.apsusc.2022.152992 doi.org/10.3390/s22145258 doi.org/10.1109/LSENS.2023.3297795



MARIA reactor: fast neutron fluence of 6.7 E17 cm⁻²

Estimated defect density: 4.0 E10 cm⁻²

MARIA reactor: fast neutron fluence of 2.0 E18 cm⁻²

Estimated defect density: 1.4 E11 cm⁻²

It takes over a dozen mln neutrons to introduce 1 defect in graphene



Summary & Conclusions

Material composition: a-Al2O3/QFS-graphene/SiC(0001)

Additional modification: low-energy ion implantation

Competitive advantages:

- operates up to 770 K (497 °C), and likely beyond
- largely resistant to neutron irradiation

Potential application: magnetic diagnostics and plasma control in fusion reactors



THANK YOU FOR YOUR ATTENTION!

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under Grant Agreement MERA.NET3/2021/83/I4BAGS/2022









Tymoteusz Ciuk, PhD

For details, please visit: www.graphene2get.com

